

REMARKS

The amendments to the specification were only to correct priority information and related application information. No new matter was added. Applicant believes that all pending claims are allowable and respectfully requests a Notice of Allowance for this application from the Examiner. Should the Examiner believe that a telephone conference would expedite the prosecution of this application, the undersigned can be reached at the telephone number set out below.

Respectfully submitted,
BEYER WEAVER & THOMAS, LLP



Steve D. Beyer
Reg. No. 31,234

P.O. Box 778
Berkeley, CA 94704-0778
(650) 961-8300

MARKED UP VERSION OF AMENDED SPECIFICATION

Please **replace** the section entitled CROSS REFERENCE TO RELATED PATENT APPLICATION with the following **amended** section:

This application claims the benefit of priority to U.S. Provisional Application 60/339,432, filed on December 11, 2001, entitled “Scanning Electron Microscope Architecture And Related Material Handling System” by George R. Koch and Douglas Masnaghetti. This application is [being filed simultaneously with]related to U.S. Patent Application number 60/339,4[32]87 filed on December 11, 2001 entitled “Transverse Magnetic Field Voltage Isolator,” by James D. Olson and Jeffery Coffer, the disclosure of which is incorporated herein by reference.